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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Shinji Maekawa
Serial No. : 09/724,403
Filed : November 27, 2000
Title : METHOD OF MANUFACTURING A SEMICONDUCTOR DEVICE WITH
TENSILE STRESS (AS AMENDED)

Art Unit : 2813
Examiner : Yennhu B. Huynh

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

TRANSMITTAL OF PRIORITY DOCUMENT UNDER 35 USC §119

Applicant hereby confirms his claim of priority under 35 USC §119 from the following application(s):

·Japan Application No. 11-336850 filed November 26, 1999

A certified copy of each application from which priority is claimed is submitted herewith.

Please apply any charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: _____

7/15/04

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